## Low frequency noise modelling in single-layer graphene FETs

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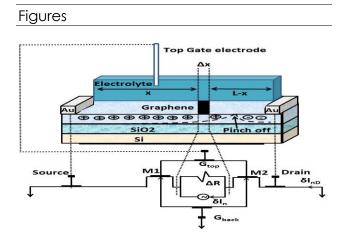
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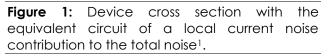
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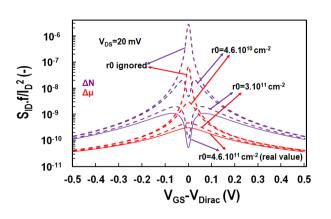
In this work, a new analytical model is proposed for low frequency noise (LFN) in single layer graphene FETs (GFETs). The model is derived based on a methodology proposed for Metal Oxide Semiconductor FETs (MOSFETs) where the device channel is divided into elementary sections<sup>1</sup>. It is then implemented considering the chemical potential-based compact model of Ref. 2. LFN fluctuations at each local section are modeled by a local current noise source as shown in Fig. 1. Data from liquid-gated GFETs<sup>3</sup> accurately validate the proposed model at different device dimensions and operating conditions. Carrier number ( $\Delta N$ ) and mobility fluctuations ( $\Delta \mu$ ) effects are the main phenomena that generate LFN in electron devices. We demonstrate that both contribute to the bias dependence of LFN in GFETs especially near the Dirac point, where the well-known M-shape<sup>4</sup> is also observed in our data. Fig. 2 illustrates that the residual charae r0 is responsible for the M-shape when  $\Delta N$  fluctuations dominate. The higher the residual charge, the more intense the M-shape predicted by the  $\Delta N$ model. The  $\Delta\mu$  model, however, follows a A-shape and its contribution can be significant near the Dirac point. A slight increase of the minimum of LFN at Dirac point when  $V_{DS}$  increases is caused by the graphene charge inhomogeneity, which is taken into account by the model.

## References

- [1] Enz C. et al., John Wiley and Sons 2006.
- [2] Landauer G. M. et al., IEEE Trans. Nanotecnolog. 13(5), 2014, 895-904
- [3] Blaschke M. B. et al., 2D Materials 4(2), 2017.
- [4] Heller I. et al., Nano Lett. 10(5), 2010, 1563-1567.







**Figure 2:**  $\Delta N$  and  $\Delta \mu$  effects at  $V_{DS} = 20 \text{ mV}$  for four different values of residual charge (r0).

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